



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/823,607  
Applicant : Albert Birner et al.  
Filed : April 14, 2004  
TC/A.U. : 2822  
Examiner : Thomas, T.  
Confirmation No. : 5077  
Docket No. : 3000.0052C  
Customer No. : 054500  
Title : A METHOD OF FORMING A SILICON  
DIOXIDE LAYER

**Mail Stop Issue Fee**

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

**ISSUE FEE TRANSMITTAL**

Transmitted herewith is an Issue Fee Transmittal (Form PTOL 85b) for the above-identified application.

Also enclosed is:

☒ Other: Certified Copy of Priority Document No. EP 01125000.8

Fees:

☒ Issue Fee of \$1400.00

☒ Other Fees: \$300.00 for Publication Fee.

Total fee: \$1700.00

Payment of Fees:

☒ Check No. 9721 in the amount of \$1,700.00 for the total fee is attached.

☐ Please charge \$\_\_\_\_\_ to Deposit Account No. 05-0460 for the total fee. This paper is being submitted in duplicate.

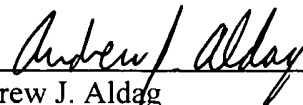
☒ The Commissioner is hereby authorized to charge any additional fees that may be required, and to credit any overpayment, to Deposit Account No. 05-0460.

Dated: June 7, 2006

**EDELL, SHAPIRO & FINNAN, LLC**  
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Respectfully submitted by  
**EDELL, SHAPIRO & FINNAN, LLC**

By:

  
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